# Chemical-Mechanical Polishing 2000— Fundamentals and Materials Issues

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# Chemical-Mechanical Polishing 2000— Fundamentals and Materials Issues

Symposium held April 26–27, 2000, San Francisco, California, U.S.A.

**EDITORS:**

**Rajiv K. Singh**
University of Florida
Gainesville, Florida, U.S.A.

**Rajeev Bajaj**
Applied Materials
Santa Clara, California, U.S.A.

**Mansour Moinpour**
Intel Corporation
Santa Clara, California, U.S.A.

**Marc Meuris**
IMEC VZW
Leuven, Belgium


**Materials Research Society**
Warrendale, Pennsylvania

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*Invited Paper

# PREFACE

This proceedings volume contains papers from Symposium E, "Fundamentals and Materials Issues in Chemical-Mechanical Polishing of Materials," held April 26–27 at the 2000 MRS Spring Meeting in San Francisco, California. Significant interest and advancements in the field were represented in more than 55 oral and poster presentations. Papers both in the application and fundamentals of CMP were presented at this conference. With the rapid emergence of copper and low dielectric constant materials, the interest in CMP is expected to further accelerate in future years.

We would like to thank all the authors, particularly the invited speakers, the session chairs and referees, all who helped to make this symposium a success. We would like to especially thank Ara Philipossian (University of Arizona), Ajoy Zutshi (Applied Materials), R. Tiwari (Texas Instruments), and S. Das (IBM) for helping us review the manuscripts. It is also our pleasure to acknowledge the support of the Department of Materials Science and Engineering and the Engineering Research Center for Particle Science and Technology at the University of Florida for financial support to this program.

Rajiv K. Singh
Rajeev Bajaj
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